

Increase performance and wafer throughput with a dual arm wafer handling system. Combined with Jabil's robust software and motion control systems, our automated wafer handling systems are designed and built to meet your exact specifications.

DUAL ARM WAFER HANDLING SYSTEM

BENEFITS

✓ FASTER CYCLE TIMES

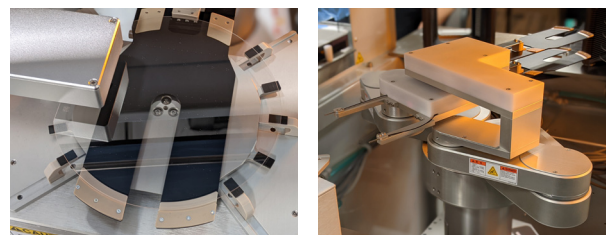
Achieve faster cycle times by maximizing robot movements within smaller spaces.

✓ INCREASE THROUGHPUT

A dual arm robot configuration provides the added flexibility needed to increase wafer production and yield.

✓ CLEAN ROOM READY

ISO Class 2 classification ensures your wafer handling system is production floor ready



Supported Wafer Sizes: Up to 300mm

Supported Wafer Types: Glass, Thin, Thick, Warped

Available Gripping Methods: Edge Grip, Vacuum

About Jabil Precision Automation Solutions

Jabil delivers high-performance, industry trusted automated wafer handling solutions for some of the world's leading semiconductor manufacturers and OEM process tool makers around the world.